

Notice of Allowability

Application No.

10/528,440

Examiner

Thao P. Le

Applicant(s)

FUJIKAWA ET AL.

Art Unit

2818

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address--

All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. **THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS.** This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.

1. ☒ This communication is responsive to 11/20/07.
2. ☒ The allowed claim(s) is/are 1,6-8,10,11,25-27 and 29-34.
3. ☒ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
 - a) ☒ All b) ☐ Some* c) ☐ None of the:
 1. ☒ Certified copies of the priority documents have been received.
 2. ☐ Certified copies of the priority documents have been received in Application No. _____.
 3. ☐ Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)).

* Certified copies not received: _____

Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application.
THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.

4. ☐ A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.
 5. ☐ CORRECTED DRAWINGS (as "replacement sheets") must be submitted.
 - (a) ☐ including changes required by the Notice of Draftsperson's Patent Drawing Review (PTO-948) attached
 - 1) ☐ hereto or 2) ☐ to Paper No./Mail Date _____.
 - (b) ☐ including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date _____.
- Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).
6. ☐ DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.

Attachment(s)

1. ☐ Notice of References Cited (PTO-892)
2. ☐ Notice of Draftsperson's Patent Drawing Review (PTO-948)
3. ☐ Information Disclosure Statements (PTO/SB/08),
Paper No./Mail Date _____
4. ☐ Examiner's Comment Regarding Requirement for Deposit
of Biological Material
5. ☐ Notice of Informal Patent Application
6. ☐ Interview Summary (PTO-413),
Paper No./Mail Date _____
7. ☒ Examiner's Amendment/Comment
8. ☒ Examiner's Statement of Reasons for Allowance
9. ☐ Other _____

DETAILED ACTION

Examiner's Amendment

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Before "Technical field", please insert:

Cross-Reference To Related Application

This application is a 371 of PCT/JP04/05649 filed on 04/20/2004, which claims benefit of Japan application 2003-122240 filed on 04/25/2003, the contents of which are hereby incorporated herein by reference in their entirety.

Response to Amendment

This Office Action is in response to Amendment filed on 11/20/2007.

Claims 31-32 have been amended.

Claims 33-34 are newly added.

Claims 1, 6-8, 10-11, 25-27, 29-34 are pending.

Remark of Applicants has been considered.

Reason for allowance

Claims 1, 6-8, 10-11, 25-27, 29-34 are allowed. The following is an examiner's statement of reason for allowance:

Claims 1, 6-8, 10-11, 25-26, 30-32: None of the references of record teaches or suggests the claimed limitations having a method of fabricating a semiconductor device by ion implanting to provide a SiC substrate at a surface with a region having dopant introduced therein, comprising the steps of providing a substrate with a mask layer including a polyimide resin film covered a first region, implanting ions to an implantation depth into the substrate at a second region of the surface of substrate free of the polyimide region film, wherein the polyimide resin film has a thickness of at least twice the implantation depth.

Claims 27, 29, 33-34: None of the references of record teaches or suggests the claimed limitations having a method of fabricating a semiconductor device comprising the steps of: a) providing a SiC substrate, b) providing a mask layer including a polyimide resin film that consists of a photosensitive polyimide resin on a first region of a surface of the substrate, by applying the polyimide resin film on the first region and a second region of the surface, then exposing the polyimide resin film to light at the first region, and then removing the polyimide resin film at the second region, wherein the step (b) does not involve photolithography employing a photoresist, c) heating the substrate to at least 300 °C and d) implanting ions while heating the substrate wherein the method does not involve chemical vapor deposition and does not involve dry etching.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably

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accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance".

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Thao P. Le whose telephone number is 571-272-1785. The examiner can normally be reached on M-F (8-6).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor Steven H. Loke can be reached on 571-272-1657. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

/Thao Le/
Thao P. Le
Primary Examiner
December 4, 2007.